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Hwa-Yaw Tam
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Introduction

The optoelectronic principle plays an outstanding role in the field of metrology and testing area as it provides an important method for the development of measurement technology. With the rapid development of information technology, the measurement technology and systems that obtain the source of information, has drawn a lot of attention. New measurement requirements appear constantly, which promotes continuous development of the optoelectronic measurement method, technology and application, to make the research on the optoelectronic measurement full of vigor and vitality.

Optoelectronic measurement research is rich in content, covering lots of areas from scientific research, manufacturing industry, to our daily life; the scope of optoelectronic measurement research expands continuously and the content continues to be more and more developed. On one hand, the traditional optoelectronic measurement research and application, represented by the background of industrial manufacturing precision measurement technology, have been constantly improving, and the concerned performances have also been improving. On the other hand, the needs of optoelectronic measurement, represented by the measurement of the digital cultural heritage protection, have been emerging ceaselessly, as well as the measuring methods and application that have developed.

More than 60 papers have been accepted into the Optoelectronic Measurement Technology and Systems branch of the OIT'2013, ranging from many research fields including optoelectronic measurement, optical instruments, spectral measurement, environment measurement, industrial measurement, optical fiber measurement, etc. These papers appropriately reflect current issues and the research level of the optoelectronic measurement field.

Jigui Zhu

